



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Confirmation No.: 2926

Group Art Unit: 3749

Filed: March 18, 2002

Examiner: Kathryn S. O Malley

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

**AMENDMENT UNDER 37 C.F.R. § 1.114(c)**

**MAIL STOP RCE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This is in response to the final Office Action of May 17, 2005. A RCE and a Petition for Extension of Time (for one (1) month) is submitted concurrently herewith, thus providing for timely filing of this Amendment by September 19, 2005 (September 17, 2005 being a Saturday).

Please amend the above-identified application as follows:

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